Author Index to Volume 23

A

Agahi, F. ..... (7) 649
Aesoph, M.D. ..... (11) 1199
Agnello, P.D. ..... (4) 413
Ahn, S.T. ..... (12) 1273
Ahrenkiel, R.K. ..... (2) 147, (7) 669
Ahuja, R. ..... (10) 1027
Airaksinen, V.M. ..... (5) 465
Akram, S. ..... (3) 259
Al-Jassim, M. ..... (11) 1229
Alavi, K. ..... (6) 519
Amarakoon, V.R.W. ..... (11) 1093, (11) 1103
Anandan, M. ..... (12) 1349
Anayama, C. ..... (3) 355
Anderson, I.E. ..... (7) 595
Anderson, R.L. ..... (11) 1159
Anderson, T.J. ..... (3) 299
Anderson, W.A. ..... (1) 13, (1) 53, (6) 551, (12) 1285
André, J.P. ..... (2) 141
Ang, S.S. ..... (6) 569
Archibald, W.B. ..... (11) 1159
Arora, B.M. ..... (2) 191
Artaki, I. ..... (8) 757, (8) 779
Asano, T. ..... (3) 263
Asbeck, P.M. ..... (4) 403
Asher, S. ..... (5) 431
Aspnes, D.E. ..... (4) 423
Attolini, G. ..... (2) 153
Averback, R.S. ..... (2) 175

B

Baca, A.G. ..... (8) 809
Badoz, P.A. ..... (6) 497
Bagai, R.K. ..... (12) 1349
Baik, H.K. ..... (12) 1335
Bajaj, J. ..... (2) 167
Baker, J.E. ..... (8) 791
Balachandran, U. ..... (11) 1087, (11) 1111, (11) 1163
Ballingall, J.M. ..... (12) 1303
Ballutaud, D. ..... (2) 239
Banerjee, S. ..... (2) 191
Bar, S.X. ..... (2) 159
Baribeau, J.-M. ..... (9) 943
Barner, J.B. ..... (9) 849
Barr, D.L. ..... (1) 63
Bartels, F. ..... (8) 787
Basco, R. ..... (7) 649
Baumann, J.A. ..... (2) 207
Bean, J.C. ..... (6) 493
Beckham, C. ..... (2) 159
Bedikjan, L. ..... (11) 1235
Bennett, B.R. ..... (4) 423
Bensahel, D. ..... (6) 565
Berkowitz, A.E. ..... (10) 1043
Berolo, O. ..... (10) 1067
Bertness, K.A. ..... (2) 195
Bhat, A.K. ..... (7) 681
Bhat, I.B. ..... (3) 259
Bhatkal, R.M. ..... (9) 907
Bhattacharya, P.K. ..... (8) 831
Bieger, W. ..... (11) 1135
Bimberg, D. ..... (2) 125, (2) 135, (2) 201
Black, M.A. ..... (11) 1121
Bodin, C. ..... (3) 313
Boettinger, W.J. ..... (7) 603
Bonnet, J.J. ..... (1) 7
Borek, M.A. ..... (9) 875
Borle, W.N. ..... (12) 1349
Bothra, S. ..... (8) 819
Boucaud, P. ..... (6) 565
Bowers, K.A. ..... (3) 251
Bradley, J. ..... (9) 919
Brebner, J.L. ..... (12) 1291
Breiland, W.G. ..... (2) 179
Bretschneider, E. ..... (3) 299
Brett, M.J. ..... (11) 1215, (12) 1309
Bright, V.M. ..... (9) 991
Brillson, L.J. ..... (9) 929
Brown, W.D. ..... (6) 569
Bruce, R. ..... (5) 441, (9) 953
Bucher, E. ..... (4) 363
Bühlmann, H.-J. ..... (12) 1343

C

Cai, Y.M. ..... (7) 653
Campbell, J.C. ..... (4) 409
Campidelli, Y. ..... (6) 497, (6) 565
Cao, W. ..... (10) 1043
Caragianis, C. ..... (9) 883, (9) 901
Cardone, F. ..... (7) 659
Carey, M.J. ..... (10) 1043
Carius, R. ..... (10) 1061
Carns, T.K. ..... (4) 369, (5) 437
Casas, L.M. ..... (9) 991
Casati, D. ..... (6) 525
Cerva, H. ..... (2) 135
Chan, C. ..... (3) 337
Chan, P.W. ..... (5) 459
Chan, Y.-J. ..... (7) 675
Chang, L.H. ..... (6) 551
Chen, H.S. ..... (7) 687
Chen, J. ..... (12) 1255
Chen, Jianhui ..... (12) 1297
Chen, K.-T. ..... (9) 963
Chen, M.-C. ..... (4) 383
Chen, Y.-J. ..... (4) 383
Cheng, H. ..... (3) 275
Chikarmane, V. ..... (12) 1261
Chilla, J.L.A. ..... (3) 359
Chin, T.P. ..... (4) 403
Chiou, J.-C. ..... (4) 383
Chiu, L.A. ..... (3) 347
Cho, C.-C. ..... (8) 827
Cholakova, T. ..... (11) 1235
Choquette, K.D. ..... (7) 625
Chou, H.C. ..... (1) 31, (7) 681
Chowdhury, R. ..... (9) 861
Christen, J. ..... (2) 125, (2) 201
Christou, A. ..... (9) 969
Chu, S.N.G. ..... (7) 625
Chun, J.S. ..... (10) 1075
Chung, D.D.L. ..... (6) 541, (6) 557, (7) 641
Chyi, J.-I. ..... (7) 675
Cibert, J. ..... (3) 313
Cinque, R.B. ..... (6) 533
Clement, M. ..... (11) 1245
Clum, J.A. ..... (8) 773
Cockerill, T.M. ..... (2) 115
Coldren, L.A. ..... (2) 87
Cole-Hamilton, D.J. ..... (2) 69
Coleman, J.J. (2) 67, (2) 115, (2) 175
Colomb, C.M. ..... (8) 791
Cook, J.W., Jr. ..... (3) 251
Cornet, A. ..... (4) 423, (9) 969
Coronado, C.A. ..... (3) 269
Corvini, P.J. ..... (2) 233
Coudenys, G. ..... (2) 225
Coudray, P. ..... (1) 7
Coyne, W. ..... (10) 1067
Cunningham, J.E. ..... (10) 1081
Cuomo, J.J. ..... (9) 889

D

Dalby, R.J. ..... (2) 207
Dalke, G. ..... (8) 787
Dang, L.S. ..... (3) 313
Dantzig, J.A. ..... (2) 115
Dapkus, P.D. ..... (2) 67
David, J.P.R. ..... (9) 975
Deering, S.E. ..... (12) 1325
del Alamo, J.A. ..... (4) 423
Deluca, J.A. ..... (11) 1191
Demeester, P. ..... (2) 121, (2) 225
DenBaars, S.P. ..... (2) 87, (2) 233
Dennis, K.W. ..... (11) 1117
DePuydt, J.M. ..... (3) 275
Deswarte, A. ..... (2) 141
Dew, S.K. ..... (11) 1215, (12) 1309
DiVenere, A. ..... (12) 1255
Domen, K. ..... (3) 355
Dorris, S.E. ..... (11) 1163,
Downey, J.P. ..... (10) 999, (10) 1007
Drost, K. ..... (7) 653
Drummond, T.J. ..... (8) 809
Dumont, H. ..... (2) 239
Durgavich, J. ..... (10) 1055
Duva, J.M. ..... (10) 1055

E

Eisen, F. ..... (4) 369
Elias, J.A. ..... (2) 105
Elliman, R.G. ..... (4) 391
Elsner, B. ..... (2) 225
Erickson, K.L. ..... (8) 721, (8) 729

F

Facemire, B.R. ..... (10) 999, (10) 1007
Fagan, J.G. ..... (11) 1093, (11) 1103
Fan, Y. ..... (3) 245
Fang, X.M. ..... (12) 1269
Fannin, L.W. ..... (2) 93
Feijóo, D. ..... (6) 493
Feldman, L.C. ..... (6) 493
Felton, L.E. ..... (7) 611, (8) 765
Fernández, J.M. ..... (12) 1297
Ferrieu, F. ..... (6) 565
Feuillet, G. ..... (3) 313

Files-Sesler, L.A. ..... (8) 827
Fine, M.E. ..... (7) 619, (8) 741
Finkman, E. ..... (2) 225
Fischer, K. ..... (11) 1135
Fisher, P.A. ..... (3) 269
Fisher, T.A. ..... (9) 975
Floyd, P.D. ..... (2) 101, (3) 283
Foad, M.A. ..... (3) 289
Foote, M.C. ..... (9) 849
Forbes, D.V. ..... (2) 115, (2) 175
Foster, D.F. ..... (2) 69
Fradkov, V.E. ..... (10) 999, (10) 1007
Franzosi, P. ..... (2) 153
Fraser, H.L. ..... (10) 1027
Frazier, D.O. ..... (10) 999, (10) 1007
Frear, D.R. ..... (8) 691
Freeman, G.B. ..... (9) 919
Freer Goldstein, J.L. ..... (5) 477
Fresina, M.T. ..... (8) 791
Freund, R.S. ..... (7) 625
Friedman, D.J. ..... (5) 431
Fu, S.-L. ..... (4) 403
Fujita, Shigeo ..... (3) 263
Fujita, Shizuo ..... (3) 263
Fukatsu, S. ..... (1) 47
Furdyna, J.K. ..... (3) 283

G

Gaines, D.G. ..... (7) 659
Gaines, J.M. ..... (3) 255
Garrou, P. ..... (8) 819
Gaskill, D.K. ..... (6) 509
Ge, Y.-R. ..... (11) 1221
Gedridge, R.W., Jr. ..... (5) 447
Georgakilas, A. ..... (9) 969
Ghosh, G. ..... (7) 619, (8) 741
Gil, R.V. ..... (2) 167
Giordana, A. ..... (6) 509
Glazer, J. ..... (8) 693
Glicksman, M.E. (10) 999, (10) 1007
Glidewell, C. ..... (2) 69
Glowacki, F. ..... (6) 565
Goldman, R.S. ..... (9) 929
Goossen, K.W. ..... (10) 1081
Gordon, H.M. ..... (8) 779
Goretta, K.C. ..... (11) 1163
Gorochov, O. ..... (2) 239
Gossard, A.C. ..... (6) 513
Gossett, K.J. ..... (3) 251
Goto, S. ..... (2) 97
Gouskov, L. ..... (1) 7
Goyal, A. ..... (11) 1169, (11) 1191
Graham, J.T. ..... (12) 1291
Green, L. ..... (2) 75
Greer, A.L. ..... (12) 1315
Grey, R. ..... (9) 975
Grober, L.H. ..... (7) 625
Grundmann, M. ..... (2) 201
Guang-Yu, W. ..... (2) 217, (2) 221
Gui, X. ..... (12) 1309
Gunshor, R.L. ..... (3) 245
Gupta, A.K. ..... (12) 1359
Gust, W. ..... (8) 787

H

Ha, Y.-M ..... (1) 39
Habermeier, H.-U. ..... (4) 363
Haddab, Y. ..... (12) 1343
Hafich, M.J. ..... (3) 359
Hagerott, M. ..... (3) 245
Haldar, P. ..... (11) 1087
Halpern, B.L. ..... (11) 1239
Han, C.-H. ..... (1) 39
Han, H. ..... (2) 115
Han, J. ..... (3) 245
Hansen, K. ..... (9) 935
Hanson, A.W. ..... (8) 791
Hanson, C.M. ..... (7) 649
Harding, C. ..... (2) 207
Hardtdegen, H. ..... (10) 1061
Harkness, S.D. ..... (9) 875
Harris, K.E. ..... (10) 1035
Hashemi, M.M. ..... (2) 101, (2) 233
Hatalis, M.K. ..... (3) 319
He, L. ..... (1) 13
He, L. ..... (12) 1285
He, L. ..... (3) 245
Heeger, A.J. ..... (5) 453, (9) 925
Heimbuch, M.E. ..... (2) 87
Heinrichsdorff, F. ..... (2) 135, (2) 201
Heremans, J. ..... (2) 75
Herko, S.P. ..... (3) 255
Hervé, D. ..... (3) 313
Hill, C.W. ..... (5) 447
Hill, G. ..... (9) 975
Hlava, P.F. ..... (7) 583
Ho, E. ..... (3) 269
Ho, I.-C. ..... (5) 471
Ho, P. ..... (12) 1303
Hoehn, J.G., Jr., ... (11) 1087
Hoellwarth, C.C. ..... (11) 1159
Höger, S. ..... (5) 453
Hogg, R.A. ..... (9) 975
Holländer, B. ..... (4) 369
Hollfelder, M. ..... (10) 1061
Holloway, P.H. ..... (3) 299
Holmes, A.L., Jr. ..... (2) 87
Holtz, P.O. ..... (6) 513
Hong, M. ..... (7) 625
Hopkins, P.L. ..... (8) 721, (8) 729
Hou, C.L. ..... (12) 1255
House, J.L. ..... (3) 269
Howard, A.J. ..... (8) 809
Hozhabri, N. ..... (6) 519
Hsieh, H.-L. ..... (5) 471
Hu, J.G. ..... (11) 1151
Huang, J.W. ..... (7) 659
Huang, L.J. ..... (9) 943
Huang, W.C. ..... (4) 397
Hull, J.R. ..... (11) 1127
Hunt, B.D. ..... (9) 849

I

legems, M. ..... (12) 1343
Irvine, S.J.C. ..... (2) 167
Ishida, K. ..... (8) 747
Ishikawa, T. ..... (3) 341
Ivey, D.G. ..... (5) 441, (9) 953
Iyer, A.N. ..... (11) 1087

J

Jackson, A.M. ..... (8) 757
Jagannadham, K. ..... (9) 861
Jäger-Waldau, G. ..... (4) 363
Jan, W.Y. ..... (10) 1081
Jen, A. K.-Y. ..... (7) 653
Jia, Q.X. ..... (1) 53, (6) 551
Jian, P. ..... (9) 953
Jiang, H. ..... (4) 391
Jin, S. ..... (7) 635, (7) 687, (8) 691, (8) 715, (8) 735
Jo, J. ..... (11) 1199
Jones, B.B. ..... (9) 849
Jones, K.M. ..... (11) 1229
Jones, K.S. ..... (3) 299
Jones, S.H. ..... (10) 1055

K

Kajuch, J. ..... (11) 1199
Kamenitsa, D. ..... (8) 801
Kamra, S. ..... (7) 681
Kanber, H. ..... (2) 159
Kang, S.H. ..... (12) 1273
Kang, S.K. ..... (8) 701
Karion, A. ..... (11) 1117
Karjalainen, P. ..... (12) 1279
Katayama, Y. ..... (2) 97
Kato, H. ..... (8) 835
Kato, Y. ..... (1) 47
Kattner, U.R. ..... (7) 603
Kavanagh, K.L. ..... (9) 929
Kawabata, A. ..... (3) 331
Kawabe, M. ..... (3) 331
Kellam, M. ..... (8) 819
Keramidas, V.G. ..... (1) 19
Kesan, V.P. ..... (4) 413
Ketterson, J.B. ..... (12) 1255
Keyes, B.R. ..... (7) 669
Khamankar, R. ..... (12) 1261
Kibbler, A.E. ..... (5) 431
Kilgo, A.C. ..... (7) 583
Killeen, K.P. ..... (2) 179
Kim, C.-K. ..... (1) 39
Kim, C.S. ..... (12) 1335
Kim, D.-W. ..... (10) 1075
Kim, E.S. ..... (12) 1273
Kim, J. ..... (12) 1261
Kim, K.H. ..... (12) 1273
Kim, S.I. ..... (12) 1335
Kim, S.T. ..... (12) 1273
Kim, T.Y. ..... (9) 901
Kimerling, L.C. ..... (5) 487
King, A.H. ..... (10) 1035
King, C.N. ..... (3) 299
Kingon, A.I. ..... (1) 57
Kistenmacher, T.J. ..... (11) 1209
Klatt, J.K. ..... (2) 175
Klavins, P. ..... (11) 1159
Klem, J.F. ..... (8) 809
Knight, G. ..... (5) 441, (9) 953
Knorr, D.B. ..... (7) 611, (10) 997

Ko, D.H. ..... (12) 1273
Koidl, P. ..... (11) 1203
Kolbas, R.M. ..... (1) 57
Kolenbrander, K.D. ..... (3) 347
Kolodziejski, L.A. ..... (3) 243, (3) 269
Kondo, M. ..... (3) 355
Kostic, P. ..... (11) 1163
Kovar, M. ..... (4) 409
Krabbes, G. ..... (11) 1135
Kramer, C. ..... (2) 195
Kramer, M.J. .... (11) 1111, (11) 1117
Krier, A. ..... (6) 503
Kroeger, D.M. ... (11) 1169, (11) 1191
Krost, A. ..... (2) 135, (2) 201
Kuech, T.F. ..... (7) 659
Kuo, L.H. ..... (3) 275
Kurtz, S.R. ..... (5) 431
Kvam, E.P. ..... (10) 1021,
..... (11) 1131, (11) 1183
Kwak, J.S. ..... (12) 1335

L

Lambert, B. ..... (1) 7
Lan, M.D. ..... (11) 1159
Lanagan, M.T. ..... (11) 1163
Landheer, D. ..... (9) 943
Langer, D.W. ..... (12) 1269
Lapasin, R. ..... (6) 525
Lappe, J.J. ..... (5) 487
Lareau, R.T. ..... (7) 649
Larré, A. ..... (6) 565
Lau, K.M. ..... (7) 649
Lau, S.S. ..... (4) 403
Lau, W.M. ..... (9) 943
Lazzarini, L. ..... (2) 153
Lee, C.L. ..... (4) 397
Lee, J. ..... (8) 831
Lee, J.C. ..... (12) 1261
Lee, S.-H. ..... (1) 39
Lee, Y.J. ..... (10) 1075
Legras, R. ..... (3) 313
Lehoczky, S.L. ..... (1) 25
Lei, T.F. ..... (4) 397
Leppävuori, S. ..... (12) 1279
Li, K.-H. ..... (4) 409
Li, L. ..... (6) 557
Li, P. ..... (11) 1215
Li, S.H. ..... (8) 831
Li, Y. ..... (12) 1269
Li, Y.F. ..... (11) 1163
Liang, B.W. ..... (11) 1251
Liang, W.-C. ..... (6) 493
Lichtenwalner, D.J. ..... (1) 57
Lie, D.Y.C. ..... (4) 369
Liedl, G.L. ..... (10) 1015, (11) 1175
Lim, D.L. ..... (8) 801
Linehan, D.S. ..... (11) 1183
Lipsanen, H.K. ..... (5) 465
Lisicka-Skrzek, E. ..... (10) 1067
Liu, W.S. ..... (5) 437
Livesay, B.R. ..... (9) 919
Llinarès, C. ..... (1) 7
Lo, V.C. ..... (5) 459
Loomans, M.E. ..... (7) 619,
(8) 741, (11) 1163
López-Rubio, J.A. ..... (11) 1245
Lovejoy, M.L. ..... (7) 669
Lowndes, D.H. ..... (9) 841
Lu, K. ..... (3) 269
Lu, Z.-H. ..... (9) 943
Luftman, H.S. ..... (7) 625
Lugagne-Delpon, E. ..... (2) 141
Lundstrom, M.S. ..... (7) 669
Luo, H. ..... (3) 283
Luquet, H. ..... (1) 7
Lüth, H. ..... (10) 1061
Lux, G. ..... (8) 801

M

M'saad, H. ..... (5) 487
Ma, C.S. ..... (5) 459
Maayan, E. ..... (2) 225
Machusak, D.A. ..... (7) 687
Mack, M.P. ..... (2) 87
Maehara, K. ..... (3) 263
Magee, C. ..... (8) 801
Mahadev, V. ..... (10) 1015
Maier, M. ..... (11) 1203
Mani, S.S. ..... (10) 999, (10) 1007
Mannaerts, J.P. ..... (7) 625
Mao, Y. ..... (6) 503
Marcenat, F. ..... (3) 313
Marshall, T. ..... (3) 255
Martin, P.A. ..... (12) 1303
Martinez, O.E. ..... (3) 359
Masuda, H. ..... (6) 577
Masur, L. ..... (11) 1191
Masut, R.A. ..... (12) 1291
McAvoy, D.T. ..... (11) 1239
McCallum, R.W. (11) 1111, (11) 1117
McCormack, M. ..... (7) 635, (7) 687
(8) 715, (8) 735
McGinn, P.J. .... (11) 1085, (11) 1121
(11) 1127, (11) 1131, (11) 1143
Mehta, P. ..... (1) 57
Melas, A.A. ..... (3) 259
Melloch, M.R. ..... (7) 669, (10) 1015
Menoni, C.S. ..... (3) 359
Merchant, H.D. ..... (7) 581
Merkel, K.G. ..... (9) 991
Merz, J.L. .... (2) 101, (3) 283, (6) 513
Messler, R.W., Jr. ..... (8) 765
Meyer, R. ..... (10) 1061
Michel, J. ..... (5) 487
Milanova, M. ..... (11) 1235
Milewski, P.D. ..... (1) 57
Millar, G. ..... (10) 1067
Miller, C.M. ..... (7) 595
Miller, D.J. ..... (11) 1151
Miragliotta, J. ..... (11) 1209
Mishima, T. ..... (6) 577
Mishra, U.K. ..... (2) 233
Mochizuki, K. ..... (6) 577
Moerman, I. ..... (2) 121, (2) 225
Molva, E. ..... (3) 313
Monahan, T.P. ..... (7) 649
Monemar, B. ..... (6) 513
Morante, J.R. ..... (9) 969
Moreland, J. ..... (2) 195
Morishita, Y. ..... (2) 97
Morris, J.W., J.r ..... (8) 691, (5) 477,
(6) 533, (8) 787,
Morris, S.J. ..... (8) 801
Motowidlo, L.R. ..... (11) 1087
Mowbray, D.J. ..... (9) 975
Murakami, M. ..... (9) 983
Murray, P.T. ..... (9) 855

N

Nakamura, T. ..... (6) 577
Narayan, J. ..... (9) 861, (9) 879
Nellis, W.J. ..... (11) 1111
Nicolet, M.-A. ..... (4) 369, (5) 437
Nimmo, K.L. ..... (8) 709
Noh, S.K. ..... (12) 1335
Nomura, Y. ..... (2) 97
Norris, P.E. ..... (2) 159
Nortron, D.P. ..... (9) 841
Nurmikko, A.V. ..... (3) 245

O

O'Neil, E.G. ..... (9) 919
Oates, A.S. ..... (1) 63
Obloh, H. ..... (11) 1203
Oh, E. ..... (3) 307
Ohta, S. ..... (3) 331
Ohtani, H. ..... (8) 747
Okada, N. ..... (3) 355
Okada, Y. ..... (3) 331
Oku, T. ..... (9) 983
Okunishi, M. ..... (9) 983
Okuno, Y. ..... (8) 835
Olson, J.M. ..... (2) 195, (5) 431
Ong, C.W. ..... (5) 459
Ono, N. ..... (9) 983
Oslin, B.L. ..... (11) 1159
Otsuka, N. ..... (10) 1015
Otsuki, A. ..... (9) 983
Ott, J.A. ..... (4) 413

P

Pabla, A.S. ..... (9) 975
Pacer, M. ..... (2) 159
Paine, D.C. ..... (9) 883, (9) 901
Pakbaz, K. ..... (5) 453, (9) 925
Park, C.-O. ..... (10) 1075
Park, C.G. ..... (12) 1335
Park, M. ..... (11) 1117
Parthasarathi, S. ..... (11) 1199
Partin, D.L. ..... (2) 75
Partis, D.A. ..... (11) 1093, (11) 1103
Pate, M.A. ..... (9) 975
Pathak, R.N. ..... (6) 519
Pathangey, B. ..... (3) 299
Patrizi, G.A. ..... (11) 1229
Pautrat, J.L. ..... (3) 313
Pavate, V. ..... (11) 1131, (11) 1183
Pearce, R.H. ..... (2) 93
Peeler, D.T. ..... (9) 855
Peiner, E. ..... (9) 935
Peiró, F. ..... (4) 423, (9) 969

Pelosi, C. ..... (2) 153
Pérotin, M. ..... (1) 7
Perrin, S.D. ..... (2) 81
Peticolas, L.J. ..... (6) 493
Petkie, R.R. ..... (9) 893
Petrich, G.S. ..... (3) 269
Petruzzello, J.A. ..... (3) 255
Poeppel, R.B. .... (11) 1127, (11) 1163
Ponzoni, C.A. ..... (3) 255
Potemski, R.M. ..... (7) 659
Powers, T.A. ..... (8) 773
Prasad, M. ..... (3) 359
Pratt, R.E. ..... (4) 375, (10) 1047
Pu, S.T. ..... (2) 125
Py, M.A. ..... (12) 1343

Q

Qin, S. ..... (3) 337
Qiu, J. ..... (3) 275
Quesnel, D.J. ..... (4) 375, (10) 1047

R

Raeder, C.H. ..... (7) 611
Raisanen, A. ..... (9) 929
Rajan, K. .... (9) 839, (9) 889, (9) 893, (9) 907, (9) 913, (10) 997
Ralston, J.D. ..... (11) 1203
Raman, R.V. ..... (11) 1159
Ramdas, A.K. ..... (3) 307
Ramesh, R. ..... (1) 19
Rao, V.P. ..... (7) 653
Ray, U. ..... (8) 779
Reaves, C.M. ..... (2) 87
Rees, G.J. ..... (9) 975
Rele, S.V. ..... (11) 1159
Ren, Z. ..... (11) 1151
Richmond-Hope, J.A. ..... (11) 1093, (11) 1103
Rieger, D.J. ..... (8) 809
Riley, G.N., Jr., ... (11) 1191
Robertson, I.M. ..... (2) 115
Robinson, G.Y. ..... (3) 359, (11) 1229
Robson, P.N. ..... (9) 975
Rocca, J.J. ..... (3) 359
Rodríguez, T. ..... (11) 1245
Rogers, J.R. ..... (10) 999, (10) 1007
Rogers, T.J. ..... (12) 1303
Rohatgi, A. ..... (1) 31, (7) 681
Roy, R. ..... (9) 889
Rui-Wu, P. ..... (2) 217, (2) 221
Ruterana, P. ..... (2) 141

S

Sagnes, I. ..... (6) 497
Sahm, P.R. ..... (11) 1127
Salamanca-Riba, L. ..... (3) 275
Sale, T.E. ..... (9) 975
Salviati, G. ..... (2) 153
Salzman, J. ..... (2) 225
Sanchez, J.E., Jr. ..... (10) 997
Sanchez-Rojas, J.L. ..... (9) 975
Sands, T. ..... (1) 19
Sanfacon, M.M. ..... (2) 147
Sangrador, J. ..... (11) 1245
Saraie, J. ..... (3) 245
Sarkhel, A.K. ..... (8) 701
Schaschek, K. ..... (11) 1239
Schatke, K. ..... (2) 135
Schätzle, P. ..... (11) 1135
Schauer, S.N. ..... (9) 991
Schetzina, J.F. ..... (3) 251, (10) 1071
Schlabach, T.D. ..... (7) 581
Schlachetzki, A. ..... (9) 935
Schmitt, J.J. ..... (11) 1239
Schmitz, J. ..... (11) 1203
Schnabel, F. ..... (2) 135
Schneider, R.P. ..... (8) 809
Selber, H. ..... (2) 125
Seltzer, C.P. ..... (2) 81
Selvamanickam, V. ..... (11) 1169
Sengupta, S. ..... (11) 1127, (11) 1143
Seraphin, A.A. ..... (3) 347
Sha, Y.-G. ..... (1) 25
Sharma, S.C. ..... (6) 519
Shealy, J.B. ..... (2) 233
Shelton, R.N. ..... (11) 1159
Shepard, A. ..... (2) 207
Sherwin, M.E. ..... (8) 809
Shi, D. ..... (11) 1127
Shi, Z.Q. ..... (1) 53
Shi, Z.Q. ..... (12) 1285
Shigesato, Y. ..... (9) 883, (9) 901
Shih, W.C. ..... (12) 1315
Shim, S.J. ..... (12) 1273
Shimomura, H. ..... (3) 331
Shin, D.W. ..... (12) 1335
Shiraki, Y. ..... (1) 47
Shul, R.J. ..... (8) 809
Silvestre, P. ..... (11) 1229
Simonton, R.B. ..... (8) 801
Singh, J. ..... (8) 831
Singh, R.K. .. (9) 839, (9) 875, (9) 913
Singler, T.J. ..... (8) 773
Sinn, M.T. ..... (4) 423
Sirtori, V. ..... (6) 525
Skolnick, M.S. ..... (9) 975
Smart, A.P. ..... (3) 289
Smith, J.F. ..... (7) 595
Smy, T. ..... (11) 1215
Solomon, J.S. ..... (12) 1269
Soonckindt, L. ..... (1) 7
Sotomayor Torres, C.M. ..... (3) 289
Specht, E.D. ..... (11) 1191
Spurdens, P.C. ..... (2) 81
Sreenivas, G. ..... (6) 569
Srivastava, A.K. ..... (2) 191
Stanev, N. ..... (11) 1235
Stillman, G.E. ..... (8) 791
Stockman, S.A. ..... (8) 791
Stringfellow, G.B. .... (2) 125, (5) 447
Stromswold, E.I. .. (4) 375, (10) 1047
Su, L.C. ..... (2) 125
Sudhama, C. ..... (12) 1261
Sugiura, K. ..... (3) 355
Sun, S.S. ..... (3) 299
Sundaram, M. ..... (6) 513
Sundersheshu, B.S. ..... (12) 1349
Sutliff, J.A. ..... (11) 1191
Svob, L. ..... (2) 239
Szekely, J. ..... (12) 1325

T

Tamura, H. ..... (8) 835
Tanahashi, T. ..... (3) 355
Tanaka, N. ..... (3) 341
Tanoue, T. ..... (6) 577
Tanzi, V.A. ..... (7) 611
Tao, M. ..... (5) 447
Tasch, A.F. ..... (8) 801
Tejwani, M. ..... (4) 413
Thiagarajan, P. ..... (11) 1229
Thomas, G. ..... (10) 1043
Tiwari, P. ..... (9) 861
Tiwari, P. ..... (9) 879
Tkaczyk, J.E. ..... (11) 1191
Todt, V.R. ..... (11) 1127
Tracy, D.M. ..... (2) 185
Tran, C.A. ..... (12) 1291
Trogolo, J.A. ..... (9) 889
Tsai, C. ..... (4) 409
Tsutsui, K. ..... (3) 289
Tu, C.W. ..... (4) 403, (11) 1251
Tu, K.N. ..... (9) 893
Turkot, B.A. ..... (2) 115

U

Uchibori, C.J. ..... (9) 983
Uusimäki, A. ..... (12) 1279

V

Vakhshoori, D. ..... (7) 625
Van Daele, P. ..... (2) 121, (2) 225
Vantomme, A. ..... (4) 369
Varanasi, C. ..... (11) 1131, (11) 1143
Varriano, J.A. ..... (1) 1
Vasquez, R.P. ..... (9) 849
Vaynman, S. ..... (8) 741
Venkatraman, C. ..... (11) 1175
Vermaerke, F. ..... (2) 121, (2) 225
Vermeire, G. ..... (2) 121, (2) 225
Vernon, S.M. ..... (2) 147
Vianco, P.T. ..... (7) 583, (8) 721 (8) 729, (8) 757, (8) 779
Voisin, P. ..... (2) 141
Volz, M.P. ..... (1) 25
von Ortenberg, M. ..... (9) 935
Voutsas, A.T. ..... (3) 319
Vreeland, T. ..... (4) 369

W

Wagner, J. ..... (11) 1203
Walck, S.D. ..... (9) 991
Walker, J.A. ..... (10) 1081
Wallace, R.M. ..... (8) 827
Wang, C.A. ..... (2) 185
Wang, D. ..... (5) 441
Wang, H.C. ..... (12) 1255

Wang, J.H. ..... (11) 1151
Wang, K.L. ..... (4) 369, (5) 437
Wang, Z.L. ..... (11) 1191
Warrier, A.V.R. ..... (12) 1359
Waters, R.G. ..... (2) 207
Watt, M. ..... (3) 289
Webb, D.W. ..... (2) 93
Wenzlaff, J.J. ..... (11) 1163
Wetzel, R.C. ..... (7) 625
White, J.M. ..... (4) 409
Whittaker, D.M. ..... (9) 975
Wickenden, A.E. ..... (6) 509
Wickenden, D.K. .. (6) 509, (11) 1209
Wicks, G.W. ..... (1) 1
Wie, C.R. ..... (1) 1
Wiedemeier, H. .... (9) 963, (11) 1221
Wieder, H.H. ..... (9) 929, (12) 1297
Wiesner, U. ..... (11) 1135
Wilkinson, C.D.W. ..... (3) 289
Willcox, A.R.K. ..... (9) 975
Williams, J.S. ..... (4) 391
Williams, L.B. ..... (11) 1131
Wilson, W.L., Jr. ..... (2) 105
Winandy, P.M. ..... (11) 1163
Wisoff, P.J. ..... (2) 105
Witherow, W.K.. (10) 999, (10) 1007
Wong, G.K. ..... (12) 1255
Wong, K.Y. ..... (7) 653
Wong, S.P. ..... (5) 459
Wood, E.P. ..... (8) 709
Woodall, J.M. ..... (10) 1015
Woodhead, J. ..... (9) 975
Woods, L.M. ..... (11) 1229
Wudl, F. ..... (5) 453

X

Xie, K. ..... (1) 1
Xu, Y. ..... (9) 919

Y

Yadava, R.D.S. . (12) 1349, (12) 1359
Yang, D. ..... (5) 441
Yang, M.-T. ..... (7) 675
Yang, S.-H. ..... (8) 801
Yang, W. ..... (8) 765
Yang, Z. ..... (10) 1071
Yeh, T.-J. ..... (7) 675
Yellen, S.L. ..... (2) 207
Yi, J. ..... (1) 53
Yi, X.J. ..... (12) 1255
Yokogawa, T. ..... (2) 101, (3) 283
Yong-Qing, D. ..... (2) 221
Yost, F.G. ..... (7) 581
Youngdahl, C.A. ..... (11) 1163
Yu, G. ..... (9) 925
Yu, J.E. ..... (3) 299
Yu, Z. ..... (3) 251
Yu, Z.Q. ..... (2) 121
Yuan, D.-W. ..... (11) 1199
Yue, C.F. ..... (9) 875

Z

Zanoni, R. ..... (11) 1239
Zhang, C. ..... (5) 453
Zhang, D. ..... (1) 57
Zhang, H.-X. ..... (12) 1279
Zhang, J.-Z. ..... (11) 1239
Zheleva, T ..... (9) 861, (9) 879
Zhu, B. ..... (4) 403
Zhu, M. ..... (6) 541, (7) 641
Zhu, Y. ..... (2) 225
Zolper, J.C. ..... (8) 809
Zwicker, G. ..... (4) 363
Zybura, M.F. ..... (10) 1055

Key Word Index to Volume 23

(111)B ..... (9) 975
123 ($YBa_2Cu_3O_{7-\delta}$) ..... (11) 1093, (11) 1103
211 (Y_2BaCuO_5) ..... (11) 1093
4f-intrashell emission ..... (12) 1269

A

absorption ..... (6) 509
acceptor ..... (5) 471
activation energy ..... (9) 935
active brazing alloy ..... (6) 541
adhesion ..... (8) 827
Ag coated Si substrates .... (12) 1279
Al-Ca ..... (12) 1315
AlAs/AlGaAs in situ reflectance monitoring ..... (2) 179
(AlGa)As ..... (10) 1061
AlGaAs/GaAs ..... (7) 649, (12) 1343
AlGaAs/InGaAs ..... (7) 675
AlGaInP ..... (3) 355
AlN ..... (6) 557
AlSb/InAs/GaSb ..... (11) 1203
aluminum ..... (1) 63
$Al_xGa_{1-x}As$ ..... (7) 659
ambipolar diffusion ..... (3) 359
amorphous Teflon ..... (8) 827
amphoteric doping ..... (4) 391
antiphase-domain boundary ..... (10) 1021
As-implantation ..... (8) 801
As-profiles in Si ..... (8) 801
atomic force microscopy ..... (8) 827
atomic hydrogen-mediated epitaxy ..... (3) 331
atomic layer epitaxy (ALE) .. (2) 185
atomic stacking ..... (10) 1027
Au/Ge/Ni ..... (5) 441
Auger microscopy ..... (6) 533
azoles ..... (8) 779

B

backscattered electrons ..... (9) 893
band gap ..... (5) 431
barium titanate ..... (5) 471
barrier height ..... (12) 1285
$(Ba_{1-x}K_x)BiO_3$ ..... (11) 1159
$BaTiO_3$ ..... (6) 551
Be ..... (6) 577
benzocyclobutene based polymer ..... (8) 819
Bi-2212 ..... (11) 1191, (11) 1199
Bi-2223 ..... (11) 1087, (11) 1191
Bi-based superconductors ..... (11) 1163
Bi/BiSb ..... (12) 1255
Bi/CdTe ..... (12) 1255
Bi-Sb-Sn isothermal section ..... (7) 619
Bi-Sb-Sn liquidus surface .... (7) 619
Bi-Sn ..... (5) 477
Bi-Sn-Sb ..... (8) 747
blanket tungsten ..... (10) 1075
bonded and etchback silicon-on-insulator (BE-SOI) ..... (6) 493
brittle fracture ..... (9) 919
broad-area lasers ..... (2) 87

C

capacitor ..... (1) 53
capacitor applications ..... (12) 1273
carbon and H_2 incorporation (2) 239
carbon implantation ..... (4) 391
carrier recombination ..... (3) 359
cathodoluminescence (CL) ..... (2) 125, (2) 201
C-doping ..... (8) 791
CdTe ..... (2) 221, (12) 1349
CdTe-CdMnTe heterostructures ..... (3) 313
CdTe/CdS ..... (7) 681
CdTe/CdS heterojunctions ..... (1) 31
characterization ..... (6) 525
charge transfer ..... (11) 1117
chemical etching ..... (8) 835
chemical vapor transport (CVT) ..... (11) 1221
chemical vapor transport (CVT) technique ..... (1) 25
chromophores ..... (7) 653
clusters ..... (9) 855
coarsening ..... (10) 1007, (10) 1015, (11) 1093
composite materials ..... (7) 641
composites ..... (6) 557
composition control ..... (11) 1251
composition variation ..... (9) 849
compound semiconductors ... (7) 625
consolidation ..... (11) 1159
contact ..... (1) 63
contact angle ..... (8) 741
contact electrical resistivity ..... (7) 641
contamination ..... (3) 337
control of ordering ..... (2) 125
copper chemical vapor deposition/ selective deposition ..... (4) 383
copper springs ..... (7) 641
creep ..... (5) 477, (7) 687
critical current density ..... (11) 1087 (11) 1111, (11) 1151, (11) 1169, (11) 1191
current-voltage characteristics ..... (10) 1071
CuSnAg solder joints ..... (10) 1047

D

deep level(s) ..... (3) 355, (5) 459, (7) 659
deep level transient spectroscopy (DLTS) ..... (12) 1343
defects ..... (3) 341, (4) 363, (6) 519, (11) 1221
deformation ..... (7) 611
deoxidization ..... (1) 7
deposition mechanism ..... (4) 383
deposition parameters ..... (4) 383
detection ..... (6) 497
diamond-like carbon (6) 569, (9) 855
dielectric(s) ..... (6) 557, (9) 875
dielectric properties ..... (6) 551
differential thermal analysis ..... (7) 595
diffusion ..... (1) 63, (8) 787, (10) 999
diffusion couples ..... (11) 1103
diisopropylantimony hydride (DIPSbH) ..... (5) 447
dimethylzinc ..... (2) 105
diode quantum well ..... (1) 47
dislocation-induced deep-level states ..... (9) 929
dislocations ..... (10) 1021, (11) 1111, (11) 1131, (11) 1183
disorder ..... (3) 283
disordering ..... (2) 101
dispersion ..... (8) 735
domain epitaxy ..... (9) 861
donor ..... (5) 471
dopants ..... (10) 1015
doping ..... (7) 659
drift ..... (1) 63
dry etching ..... (3) 289
DX center ..... (12) 1343

E

elastic properties ..... (11) 1199
electrical characterization ... (3) 255
electrical contacts ..... (10) 1071
electrical properties ..... (4) 403
electroluminescence ..... (1) 47
electroluminescence (EL) .... (3) 263, (6) 503
electroluminescent thin films ..... (3) 299
electromigration ..... (1) 63
electron ..... (11) 1151
electron backscattered diffraction (EBSD) ..... (9) 893
electron beam induced current (EBIC) ..... (4) 363
electron microscopy ..... (10) 1035, (11) 1131
electron mobility ..... (2) 75, (2) 141
electron relaxation time ... (12) 1297
electron-beam induced damage ..... (3) 341
electronic assembly ..... (8) 693, (8) 757
electroreflectance (ER) ..... (6) 509
ellipsometry ..... (4) 423,(6) 565
energy band offsets ..... (6) 503
Epi-Ge ..... (5) 437
epilayer/substrate interface ..... (7) 649
epitaxial grain growth ..... (11) 1175
epitaxy ..... (2) 75, (3) 251, (9) 861 (9) 879, (9) 907, (10) 1043
erbium ..... (12) 1269
etch stop ..... (6) 493
ethylene diamine pyrocatechol ..... (6) 493
exchange coupling ..... (10) 1043

excimer laser ..... (9) 855

F

faceting ..... (9) 907
ferroelectric PZT ..... (12) 1261
ferroelectrics ..... (1) 19, (9) 875, (9) 879
field effect transistors (FETs) ..... (4) 413
film-flow resistance ..... (9) 841
film-growth mechanisms ..... (9) 841
fluorine ..... (10) 1075
fluorine ion-implantation ..... (1) 13
flux pinning ..... (11) 1111, (11) 1183
fluxless soldering ..... (6) 533
fracture ..... (7) 611
fracture toughness ..... (4) 375, (10) 1047

G

GaAs ..... (1) 13, (2) 69, (2) 75, (2) 97, (2) 121, (2) 185, (4) 391, (4) 397, (6) 577, (8) 809, (9) 943, (9) 991, (12) 1335
$(GaAs)_n(InAs)_n$ short period superlattices ..... (2) 141
GaAs metal semiconductor field-effect transistor (MESFET) devices ..... (2) 159
GaAs molecular beam epitaxial growth ..... (10) 1081
GaAs-AlGaAs ..... (1) 1,(6) 513
GaAs/InP heterostructure ..... (2) 153
GaAs/Si ..... (10) 1021
GaAs:In ..... (11) 1235
GaInAs ..... (2) 81
GaInAsP ..... (2) 81
GaInP ..... (2) 125, (4) 403, (5) 431
gallium arsenide-germanium alloy ..... (2) 147
gallium diffusion barrier .. (10) 1081
gallium nitride ..... (11) 1209
GaN ..... (6) 509
gas source molecular beam epitaxy (GSMBE) ..... (3) 269, (11) 1229, (11) 1251
GaSb ..... (1) 7, (2) 217
GeMoW ..... (9) 991
GeSi ..... (4) 369
$GeSiO_2$ reduction ..... (5) 437
Ginzburg-Landau Coulomb gas ..... (9) 841
grain alignment ..... (11)1151
grain alignment (texturing) ..... (11) 1143
grain boundary diffusion ..... (12) 1309
grain boundary misorientation ..... (9) 893
grain growth ..... (9) 913, (10) 1035 (11) 1103
grain size ..... (6) 577
grain size distribution ..... (9) 889
graphite ..... (9) 855
green emitting light-emitting diodes (LEDs) ..... (5) 453
growth chemistry ..... (7) 659
growth kinetics ..... (2) 217, (7) 583
growth mechanisms ..... (2) 69
growth rates ..... (10) 1055

H

H_2 annealing ..... (5) 437
Hall effect ..... (3) 255, (11) 1245
Hall effect measurements .... (3) 245
halogen ..... (5) 487
He^+ ion implantation ..... (4) 403
heavy and light hole mobilities ..... (12) 1359
heteroepitaxy ..... (10) 1021
heterojunction solar cells ..... (7) 681
heterojunctions ..... (6) 503
heterostructure(s) .... (3) 341, (4) 423 (9) 929, (11) 1203
heterostructure field-effect transistor ..... (7) 675
$Hg_{1-x}Cd_xTe$ ..... (9) 963
HgCdTe ..... (1) 25, (2) 167, (2) 221, (11) 1221
HgCdTe crystals ..... (12) 1359
HgCdTe implantation ..... (11) 1245
high electron mobility transistor (HEMT) ..... (12) 1303
high pressure oxidation ..... (9) 901
high resolution TEM ..... (10) 1027
high resolution x-ray diffractometry (HRXRD) ..... (2) 153
high-electron mobility transistor (HEMT) structure ..... (2) 141
high-resolution x-ray diffraction (HRXRD) ..... (12) 1291
hillocks ..... (10) 1035
hole effective mass ..... (9) 935
hole mobility ..... (3) 245
holography ..... (10) 999
hydrothermal oxidation ..... (9) 883

I

II-VI semiconductor (2) 101, (3) 283
II-VI ternary and quarternary alloys ..... (3) 307
III-IV on Si ..... (2) 201
III-V-IV_2 compound ..... (2) 147
immersion tin ..... (8) 779
implantation ..... (1) 39
implantation model ..... (8) 801
impurities ..... (3) 337
In activation ..... (11) 1245
in situ monitoring ..... (2) 167
in-situ analysis ..... (6) 565
in-situ process ..... (7) 625
In-Sn ..... (5) 477
$In_{0.08}Ga_{0.92}As/GaAs$ ..... (9) 929
InAlAs ..... (9) 969
InAlAs/InGaAs heterojunctions ..... (12) 1297
InAlGaAs/GaAs ..... (2) 207
InAsP/InP ..... (12) 1291
InAsSb ..... (6) 503
increased by electrical resistivity ..... (7) 641
indium phosphide ..... (2) 195
infrared ..... (6) 497
InGaAs .... (8) 791, (9) 991, (12) 1303
(In)GaAs/(Al)GaAs ..... (2) 225
InGaAs/GaAs ..... (2) 175, (2) 191
InGaAs/GaAs multiple quantum well (MQW) ..... (9) 975
InGaAs/GaAs/AlGaAs ..... (2) 115
InGaAs/InP ..... (2) 87
InGaAs(P)/InP ..... (2) 225
InGaAsP ..... (11) 1229
(In,Ga)P ..... (3) 269
InGaP/InAlP multiple quantum well ..... (3) 359
InP ..... (2) 233, (4) 423, (5) 441, (5) 459, (9) 943, (9) 953, (9) 969
InP on Si ..... (2) 135
InP/Si ..... (2) 201
InSb ..... (2) 75
interconnects ..... (12) 1315
interdiffusion ..... (2) 191, (11) 1221
interface(s) ..... (11) 1221, (12) 1255
interface solid state reactions ..... (9) 953
interface state density ..... (9) 943
interface states ..... (12) 1291
interfacial diffusion ..... (8) 729
interfacial reaction ..... (8) 721
interlevel dielectric ..... (8) 819
intermetallic compound(s) .. (7) 583, (8) 721, (8) 787
intermetallic growth ..... (8) 729
intermetallic precipitates ..... (9) 919
intermetallics ..... (4) 375, (8) 765
internal photoemission ..... (6) 497
intervalence scattering .... (12) 1359
$In_xGa_{1-x}As$ ..... (9) 983
$In_yGa_{1-y}As_{1-x}P_x$ ..... (11) 1251
ion implantation ..... (3) 337, (5) 459
ionization energy ..... (9) 935
irradiation damage ..... (4) 369
isothermal aging ..... (7) 611
isothermal capacitance transient spectroscopy (ICTS) ..... (3) 355

J

jet vapor deposition ..... (11) 1239
junction field effect transistor (JFET) ..... (2) 233, (8) 809

K

kinetics ..... (10) 999, (10) 1007, (11) 1251

L

laser ..... (1) 1
laser ablation ..... (3) 347, (9) 849 (9) 861, (9) 875, (9) 879, (12) 1279

laser ablation film growth ... (9) 841
laser-soldering ..... (8) 765
lateral metalorganic molecular beam epitaxy (MOMBE) ..... (2) 97
lattice mismatch ..... (9) 969
lattice vibrations ..... (3) 307
lattice-mismatched heteroepitaxy ..... (3) 331
lead free .....(7) 635, (8) 693, (8) 701 (8) 709, (8) 735, (8) 757
lead-free solder(s) .... (7) 595, (7) 687 (8) 765, (8) 715, 8) 741
levitation force ..... (11) 1127
light emission ..... (1) 57
linear electro-optic coefficients ..... (7) 653
liquid phase additives ..... (11) 1103
liquid phase epitaxy (LPE)..... (6) 503, (11) 1235
local modes..... (3) 307
low pressure chemical vapor deposition (LPCVD) ..... (3) 319
low pressure metalorganic vapor phase epitaxy..... (10) 1061
low pressure organometallic vapor phase epitaxy..... (2) 159, (7) 649
low temperature GaAs ..... (10) 1015
LT-GaAs..... (6) 519
luminescence ..... (3) 289
luminescent polymer..... (5) 453

M

magnetization ..... (11) 1127, (11) 1143, (11) 1159
magnetron sputter deposition ..... (11) 1215
magnetron sputtering ..... (12) 1261
mechanical properties ..... (8) 715
mechanics ..... (12) 1325
melt processing..... (11) 1135
melt quenched ..... (11) 1093
melt texture ..... (11) 1121
melt-textured Y123 ..... (11) 1111
melt-texturing ..... (11) 1127
melting point ..... (8) 709
memory applications ..... (12) 1261
metal thick film conductor ... (6) 541
metal/InP interface ..... (12) 1285
metallization..... (1) 63, (4) 383, (8) 773, (12) 1309, (12) 1335
metalorganic chemical vapor deposition (MOCVD)..... (1) 31, (2) 93, (2) 147, (2) 175, (2) 179, (2) 115, (2) 233, (2) 239, (3) 299, (8) 791, (11) 1209, (12) 1269, (12) 1291
metalorganic decomposition ..... (11) 1175
metalorganic vapor phase epitaxy (MOVPE) ....(2) 81, (2) 135, (2) 69, (2) 101, (2) 141, (2) 153, (2) 191, (2) 217, (2) 221, (3) 355, (7) 659
metalorganic vapor phase epitaxy (MOVPE) reactor..... (2) 167
methyl radical absorption .... (2) 105
Mg implants..... (8) 809
microscopy ..... (11) 1151
microstructure ..... (5) 477, (8) 715, (8) 735, (9) 889, (9) 913, (10) 1043
microstructure coarsening..... (10) 999, (10) 1007
Mie theory..... (12) 1349
minority carrier lifetime ..... (3) 331
minority hole mobility..... (7) 669
mirror surface..... (8) 835
miscibility gap ..... (9) 963
misfit dislocation nucleation in ZnSe ..... (3) 275
misfit stress ..... (9) 861
mixed-phase silicon ..... (3) 319
mobility ..... (3) 255
mobility effective mass..... (12) 1359
modeling ..... (10) 1055, (12) 1325
modified random element isodisplacement (MREI) mode..... (3) 307
modulation doping..... (3) 299
modulation-doped field-effect transistor (MODFET) ... (12) 1343
molecular beam deposition .. (6) 577
molecular beam epitaxy (MBE) ..... (1) 1, (1) 47, (3) 313, (3) 331, (5) 465, (6) 519, (7) 625, (7) 675, (11) 1203, (12) 1297, (12) 1343
morphological stability..... (9) 907
multi-mode behavior ..... (3) 307
multi-quantum well laser structures ..... (2) 81
multilayers..... (9) 879, (10) 1027
multiple quantum well (MQW) ..... (12) 1291

N

n^+-GaAs ..... (7) 669
n-type GaAs ..... (9) 983
nano wires..... (2) 97
nanocrystalline synthesis .... (9) 901
nanolithography ..... (3) 289
nanostructures ..... (3) 289
narrow gap semiconductor..... (2) 75
$Nd_{1+x}Ba_{2-x}Cu_3O_{7+\delta}$ ..... (11) 1117
$Nd_{1+x}Ba_{2-x}Cu_3O_y$ ..... (11) 1127
nitridation..... (10) 1067
nitrogen carrier gas..... (10) 1061
nitrogen doping ..... (3) 263, (6) 569
nitrogen p-type doping ..... (3) 269
nonlinear susceptibility ... (11) 1209
nonplanar metalorganic vapor phase epitaxial growth ..... (2) 121
nonradiative recombination center ..... (3) 355
nucleation model ..... (3) 319

O

ohmic contact(s)..... (3) 245, (4) 397, (5) 441, (9) 953, (9) 983, (9) 991
optical absorption ..... (12) 1349
optical anisotropy (OA) ..... (4) 423
optical gain ..... (3) 313
optocoupler ..... (9) 925
optoisolator ..... (9) 925
order-disorder ..... (5) 431
organic-ceramic films ..... (11) 1239
organometallic epitaxy..... (3) 259
organometallic vapor phase epitaxy (OMVPE) ..... (2) 125, (2) 185, (2) 195, (5) 447, (6) 509
Ostwald ripening ..... (10) 999, (10) 1007
oxidation .....(6) 533, (8) 709, (9) 883
oxide films...(9) 861, (9) 875, (9) 913
oxide heterostructures ..... (1) 19
oxygen .....(1) 39, (7) 659, (11) 1121
oxygen impurity ..... (3) 355
oxygen partial pressure ... (11) 1117

P

p-doping ..... (3) 259
p-type ZnSe ..... (3) 275, (10) 1071
packaging..... (8) 701
palladium ..... (11) 1121
pancake coils..... (11) 1087
passivation ..... (1) 7
patterned substrate..... (2) 201
Pb-free solder..... (7) 687
phase diagram ..... (7) 603, (8) 747, (11) 1135
phase equilibria ..... (11) 1135
phase transformation ..... (10) 999 (10) 1007
photo-assisted metalorganic vapor phase epitaxy..... (3) 263
photocurrent loss ..... (7) 681
photodissociate ..... (2) 105
photoluminescence (PL) ..... (3) 251, (3) 259, (3) 269, (3) 341, (3) 347, (4) 409, (6) 513, (5) 459, (6) 565, (8) 831, (11) 1229, (12) 1303
photoluminescence decay ..... (3) 331
photoreflectance (PR) ..... (5) 465, (6) 509
physical vapor transport (PVT) technique ..... (1) 25
piezoelectric ..... (9) 975
pinning of dislocations by stacking faults ..... (3) 275
planar doping..... (12) 1343
plasma etching ..... (8) 827
plasma immersion ..... (3) 337
plasma-enhanced chemical vapor deposition (PECVD) ..... (6) 569
polycrystal ..... (6) 577
polymer-matrix..... (6) 557
polymers..... (7) 653
polysilicon thin film transistors (TFT)..... (1) 39
porous Si ..... (4) 409
positive temperature coefficient resistor (PTCR) ..... (5) 471
precipitate(s)..... (7) 635 (10) 1015, (12) 1315, (12) 1349
precursors ..... (2) 69

preferential film growth... (11) 1175
pulsed laser deposition..... (9) 855
pyrolysis ..... (5) 447
PZT piezoelectric films ..... (12) 1279

Q

quantitative phase analysis..... (11) 1093
quantum efficiency ..... (5) 453
quantum well(s)(QW)... (1) 1, (2) 87, (2) 191, (6) 513
quantum well lasers ..... (2) 115, (2) 207
quantum well wire (QWW) laser ..... (2) 121
quantum well wires..... (8) 831
quasi-stationary diffusion ..... (10) 1007

R

radio frequency (rf) sputtering ..... (9) 983
radio frequency sputter etching ..... (11) 1215
Raman scattering ..... (3) 289
rapid thermal annealing (RTA).....(1) 1, (1) 13, (4) 397, (5) 459, (11) 1245
rapid thermal processing ..... (11) 1175
rare earths ..... (12) 1269
reaction kinetics ..... (2) 221
reactive ion etching/reactive ion beam etching ..... (4) 363
recombination velocity ..... (5) 487
recrystallization ..... (11) 1169
reflectance difference spectroscopy (RDS) ..... (4) 423
refractory metals ..... (9) 991, (11) 1215
reliability .....(1) 63, (2) 207, (8) 701
resistivity (5) 471, (6) 577, (10) 1027
rheology..... (6) 525
Rodrigues-Frank (R-F) space ..... (9) 893
Rutherford backscattering (RBS)..... (2) 175

S

S ..... (1) 7
Sb compounds ..... (5) 447
scanning electron microscopy ..... (7) 595
scattering factor ..... (12) 1359
scattering mechanisms .... (12) 1359
screening length ..... (12) 1359
secondary ion mass spectroscopy (SIMS)..... (2) 175, (3) 355
seeding ..... (11) 1127
selective area ..... (2) 115
selective area epitaxy of GaAs ..... (2) 159
semi-insulating layers..... (2) 135
semiconducting polymer ..... (9) 925
shadow masked metalorganic vapor phase epitaxy..... (2) 225
shock-compaction ..... (11) 1111
Si .....(5) 437, (8) 801, (12) 1273
Si complementary metal oxide semiconductor ..... (10) 1081
Si interface control layers ... (9) 943
Si ion irradiation ..... (4) 369
Si nanocrystallites..... (3) 347
Si substrates ..... (6) 551
Si-Co-Ga-As quaternary phase diagram..... (12) 1335
Si-Ge alloys ..... (9) 883, (9) 901
Si/Co/GaAs ..... (12) 1335
SiC whiskers..... (6) 557
SiGe.....(1) 47, (4) 413, (6) 493
SiGe/Si quantum wells..... (8) 831
silicide ..... (6) 497
silicon ..... (4) 363, (5) 487
silicon nanoparticles ..... (1) 57
silicon nitride/oxide ..... (12) 1273
silicon surface chemistry ..... (5) 487
silicon-germanium growth ... (6) 565
silicon-on-insulator..... (6) 493
silicone matrix ..... (7) 641
silver ..... (11) 1121
simulation ..... (3) 341
sintering..... (5) 471, (11) 1163
SiO_2/Si substrates..... (1) 19
SiO_x nanoparticles ..... (1) 57
Sn-Bi-Ag..... (7) 603
Sn-Bi/Cu..... (7) 611
Sn-Pb solder..... (4) 375
Sn/Cu ..... (9) 919
solar cells ..... (1) 31, (3) 331
solder(s)..... (7) 583, (7) 603, (7) 635, (7) 641, (7) 687, (8) 693, (8) 701, (8) 709, (8) 721, (8) 729, (8) 735, (8) 757, (8) 773, (8) 787, (12) 1325
solder alloys ..... (7) 619
solder joints ..... (7) 611
solder materials..... (8) 747
solder paste..... (6) 525
solderability ..... (8) 757, (8) 779
solid phase crystallization ..... (1) 39
solid solution(s).... (9) 963, (11) 1117
solidification ..... (7) 603, (11) 1093, (11) 1135
sputtering ..... (1) 53
stable delivery rate..... (2) 93
stacking faults ..... (3) 255, (11) 1111
stimulated emission ..... (3) 313
strain..... (9) 975
strain relaxation..... (2) 191, (3) 275
strain tensile tests..... (9) 919
strained layer ..... (2) 201, (2) 207
strength..... (7) 635
structural transition ..... (10) 1027
submicron gratings ..... (2) 121
substrate orientation..... (2) 195
substrate surface characteristics ..... (11) 1175
substrate surface roughness ..... (10) 1047
sulfuration ..... (1) 7
superconductivity ..... (9) 841
superconductor .... (9) 849, (11) 1183
superlattice(s) ..... (2) 101, (2) 175 (3) 283, (5) 465, (9) 841
superlattice films..... (12) 1255
supersonic expansion ..... (3) 347
surface chemistry ..... (4) 409
surface finish ..... (8) 779
surface morphology ..... (2) 195
surface passivation.. (3) 347, (5) 487
surface state density ..... (12) 1285
surface-reaction-limited growth ..... (2) 185
surfactant ..... (8) 827
synthesis ..... (11) 1159, (11) 1163

T

tertiarybutylphosphine ..... (2) 233
tertiarylbutylarsine..... (12) 1291
texture.....(9) 889, (9) 913, (10) 1035 (11) 1169, (11) 1191
texturing ..... (11) 1103
thermal coefficient of resistance..... (10) 1067
thermal conductivity ..... (6) 557
thermistor ..... (5) 471
thermodynamics ..... (7) 603
thermomechanical processing ..... (11) 1087
thin films ..... (1) 53, (9) 849, (11) 1239, (12) 1261, (12) 1335
thin film capacitors ..... (6) 551
thin film resistors ..... (10) 1067
thin-film diffusion barriers ..... (12) 1309
third-harmonic generation..... (11) 1209
three-dimensional simulation..... (12) 1309
three-dimensional interconnected network ..... (7) 641
TiN ..... (10) 1075
tin content..... (8) 773
tin-silver-copper eutectic ..... (7) 595
titanium germanide ..... (4) 413
titanium nitride..... (12) 1309
titanium silicide ..... (4) 413
Tl-1223 ..... (11) 1191
Tl-Ba-Ca-Cu-O..... (11) 1151
transmission electron microscopy (TEM).. (2) 153, (9) 969, (11) 1111, (12) 1315
trap state density ..... (1) 39
trilayers ..... (9) 841
trimethylindium (TMIn) ..... (2) 93
two-dimensional electron gases (2DEG) ..... (12) 1297

U

ultrasonic characterization ..... (11) 1199

V

valved As cracker ..... (11) 1203
vapor phase selective epitaxy ..... (10) 1055
very large scale integrated (VLSI) circuits ..... (8) 819
via ..... (1) 63
visible laser ..... (3) 313
volume electrical resistivity ..... (7) 641
vortices ..... (9) 841

W

W/TiN interface ..... (10) 1075
W:Ti ..... (10) 1067
wafer bonding ..... (6) 493
wavelength dispersive spectrometry ..... (7) 595
wavelength tuning ..... (2) 115
wettability ..... (7) 687, (8) 741
wetting ..... (8) 773, (8) 779
Wulff plot ..... (9) 907

X

x-ray diffraction ..... (5) 465, (7) 595 (9) 963, (11) 1159
x-ray photoelectron spectroscopy (XPS) ..... (3) 289, (8) 827

Y

Y-123 ..... (11) 1191
Y123 ..... (11) 1121
Y_2BaCuO_5 ..... (11) 1131, (11) 1143
$YBa_2Cu_3O_7$ ..... (11) 1131, (11) 1183
$YBa_2Cu_3O_x$ ..... (11) 1127
YBCO ..... (11) 1135
yttrium ..... (11) 1093

Z

zero-field time-of-flight (ZFTOF) technique ..... (7) 669
zinc absorption ..... (2) 105
zinc selenide ..... (3) 251, (3) 259
Zn implants ..... (8) 809
Zn-doped InP ..... (9) 935
ZnCdSe/ZnSe quantum well (3) 263
ZnMgSSe:Cl ..... (3) 255
ZnS ..... (3) 299
ZnSe ..... (2) 105, (3) 245, (3) 263, (3) 269, (3) 289, (8) 835
ZnSe:N ..... (3) 251
ZnTe ..... (2) 239, (3) 245, (3) 289